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APPLICATION NO.	FILI	NG DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO. CONFIRMATION !		
09/785,815	02/16/2001		Yeuk-Fai Edwin Mok	4969/USA/ISM/COPPER/SB 4127		
32588	7590	01/07/2004		EXAMINER		
APPLIED MATERIALS, INC. 2881 SCOTT BLVD. M/S 2061				MACARTHUR, SYLVIA		
SANTA CL				ART UNIT	PAPER NUMBER	
				1763		

DATE MAILED: 01/07/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)	
	09/785,815	MOK ET AL.	
Office Action Summary	Examiner	Art Unit	
	Sylvia R MacArthur	1763	
The MAILING DATE of this communication aperiod for Reply	ppears on the cover sheet w	ith the correspondence address	
A SHORTENED STATUTORY PERIOD FOR REP THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a re If NO period for reply is specified above, the maximum statutory perior. - Failure to reply within the set or extended period for reply will, by statt. - Any reply received by the Office later than three months after the mail- earned patent term adjustment. See 37 CFR 1.704(b).		reply be timely filed ty (30) days will be considered timely. ITTHE from the mailing date of this communicati 3ANDONED (35 U.S.C. § 133).	ion.
1) Responsive to communication(s) filed on 27.	August 2003.		
2a)⊠ This action is FINAL . 2b)□ Thi	s action is non-final.		
Since this application is in condition for allow closed in accordance with the practice under			is
isposition of Claims			
4) Claim(s) 1-13 and 23-37 is/are pending in the	e application.		
4a) Of the above claim(s) is/are withdr	awn from consideration.		
5) Claim(s) is/are allowed.			
6)⊠ Claim(s) <u>1-13 and 23-37</u> is/are rejected.			
7) Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction and/	or election requirement.		
pplication Papers			
9)☐ The specification is objected to by the Examir	ner.		
10)⊠ The drawing(s) filed on 16 February 2001 is/a	re: a) accepted or b) □	objected to by the Examiner.	
Applicant may not request that any objection to the			
Replacement drawing sheet(s) including the corre	, .	• •	(d).
11) The oath or declaration is objected to by the E	Examiner. Note the attached	d Office Action or form PTO-152.	
riority under 35 U.S.C. §§ 119 and 120			
12) Acknowledgment is made of a claim for foreign	gn priority under 35 U.S.C.	§ 119(a)-(d) or (f).	
a) All b) Some * c) None of: 1. Certified copies of the priority documer 2. Certified copies of the priority documer 3. Copies of the certified copies of the pri application from the International Burea	nts have been received in A ority documents have been		
* See the attached detailed Office action for a lis 13) ☐ Acknowledgment is made of a claim for domes since a specific reference was included in the fi 37 CFR 1.78.	tic priority under 35 U.S.C. rst sentence of the specific	§ 119(e) (to a provisional applica ation or in an Application Data Sh	
 a) ☐ The translation of the foreign language pi 14) ☐ Acknowledgment is made of a claim for domes reference was included in the first sentence of the translation. 	tic priority under 35 U.S.C.	§§ 120 and/or 121 since a specif	
achment(s)			
Notice of References Cited (PTO-892)		Summary (PTO-413) Paper No(s).	
_ ``	5) Notice of Ir	iummary (PTO-413) Paper No(s) formal Patent Application (PTO-152)	

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DETAILED ACTION

Election/Restrictions

1. Applicant's election of claims 1-13 in the paper sent 8/27/03 is acknowledged. Because applicant did not distinctly and specifically point out the supposed errors in the restriction requirement, the election has been treated as an election without traverse (MPEP § 818.03(a)).

Claim Rejections - 35 USC § 102

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 3. Claims 1, 2, 4-10, 24, 25, and 27-33 are rejected under 35 U.S.C. 102(e) as being anticipated by Hey et al (US 6,551,488).

Regarding Claim 1, 5, 24, and 28: Hey et al teaches the segmenting of a processing system into wet and dry areas. The mainframe 214 comprises a transfer station 216 (transfer position), a spin-rinse dry (SRD) station 212 (rinse position), and an IBC system 235 (etch position), see col. 5 lines 12-62.

A plurality of nozzles are described as being articulated to a variety of positions the first nozzles extend fluid onto the top of the substrate while the second nozzles extend fluid onto the bottom of the substrate.

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Regarding the cooperatively movable nozzles is a matter of intended use that the nozzles dispense etchant since the nozzles of Hey are inherently capable of dispensing etchant.

Regarding claims 2 and 25: The wafer orientor 230 (substrate centering hoop) positions each wafer 234 in a desired orientation to ensure that the wafer is properly processed.

Regarding claims 4, 27, and 33: Hey teaches that the unwanted deposits are removed from the edge exclusion zone by the adjustment of the nozzles, see col.8 lines 5-18.

The pedestal actuator 334 rotates the pedestal to spin the substrate and raises and lowers the pedestal. The system of Dordi also adjusts the orientation and placement of nozzles so that the unwanted deposits can be removed along the edge of the substrate to create an edge exclusion zone. The fluid/chemical delivery assembly 2106 comprises one or more nozzles 2150 disposed on one or more dispense arms 2152 which dispenses rinsing fluid and etchant. The dispense arm 2152 includes one ore more conduits extending through the dispense arm for connecting the nozzle 2150 to an etchant source.

The loading station transfer robot 228 (actuator) also transfers wafer 234.

Regarding claims 6 and 29: Hey et al teaches in col. 27 lines 57-64 that slit valve 922 is provided as an assess route for the transfer robot. Fig. 2 illustrates its proximity to the transfer position.

Regarding claims 7 and 30: Col. 6 lines 5-8 discusses that he pedestal actuator 334 rotates the pedestal to spin the substrate and raises and lowers the pedestal, this is illustrated as a spindle assembly in Fig. 4.

Regarding claims 8 and 31: Col. 6 lines 13-15 that a vacuum chuck is used.

Regarding claims 9 and 32: The articulating member anticipates a dispensing arm.

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Regarding claim 10: Hey teaches that the unwanted deposits are removed from the edge exclusion zone by the adjustment of the nozzles, see col.8 lines 5-18. It is a matter of intended use that the nozzles dispense etchant rather than rinsing fluid. The nozzles of Hey are inherently capable of dispensing etchant.

Allowable Subject Matter

4. Claims 3, 11-13, 23, 26, and 34-37 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

The prior art of record fails to teach or fairly suggest a rotatable a centering hoop rinsing nozzle and a dispensing arm assembly.

Conclusion

Response to Arguments

5. Applicant's arguments with respect to claims 1-13 have been considered but are moot in view of the new ground(s) of rejection. The limitation of "cooperatively movable nozzles required further search, consideration, and thus a new grounds of rejection.

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after

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the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sylvia R MacArthur whose telephone number is 571-272-1438. The examiner can normally be reached on M-F during the core hours of 8 a.m. and 2 p.m..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory L. Mills can be reached on 703-308-1633. The fax phone numbers for the organization where this application or proceeding is assigned are 703-872-9306 for regular communications and 703-872-9306 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0661.

Mualla La La December 19, 2008

Sylvia R MacArthur Patent Examiner Art Unit 1763

> P. Hassonzedol primary Examiner AV 1763